SAND2006-3302P

Sandia National Laboratories is actively soliciting an industry partner to further develop and commercialize electrooptical/optomechanical technologies for advanced lithographic applications. Building on our experience developing an R&D 100 Award-winning extreme ultraviolet lithography full-field step-scan system, we are seeking to utilize the capabilities developed for this and other programs to address the current issues being faced by the microelectronics industry. Suitable projects include (but are not limited to) thermal and mechanical modeling from the component to the system level, developing and testing components, and integration of components into subsystems and complete lithographic systems.

Sandia National Laboratories is seeking partners to join us in this exciting effort. Of particular value would be industrial participants with experience in providing a path to market following a successful prototype demonstration. Partnerships may take the form of Cooperative Research & Development Agreements (CRADA) and/ or commercial licenses. Commercial licensees will have the option to obtain, up to and including, an exclusive license to the intellectual property in a pre-negotiated, defined field of use for reasonable compensation. CRADAs are expected to include funds-in to the Lab.

If your company has the technical capability and manufacturing capacity to produce these devices for government and commercial applications, and if you wish to pursue this unique opportunity, please email a brief description of your company, your contact information, and your interests in this venture to: clburch@sandia.gov. You will be contacted by a business representative who will discuss the requirements and steps for working with Sandia. Please respond no later than Xxxber yy, 2006.